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Design aspects of $\text{Bi}_2\text{Sr}_2\text{CaCu}_2\text{O}_{8+\delta}$ THz sources: optimization of thermal and radiative properties

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Abstract

Impedance matching and heat management are important factors influencing performance of THz sources. In this work we analyze thermal and radiative properties of such devices based on mesa structures of a layered high-temperature superconductor $\text{Bi}_2\text{Sr}_2\text{CaCu}_2\text{O}_{8+\delta}$. Two types of devices are considered, containing either a conventional large single crystal, or a whisker. We perform numerical simulations for various geometrical configurations and parameters and make a comparison with experimental data for the two types of devices. It is demonstrated that the structure and the geometry of both the superconductor and the electrodes are playing important roles. In crystal-based devices an overlap between the crystal and the electrode leads to appearance of a large parasitic

25 capacitance, which shunts THz emission and prevents impedance matching with open space. The
26 overlap is avoided in whisker-based devices. Furthermore, the whisker and the electrodes form a
27 turnstile (crossed-dipole) antenna facilitating good impedance matching. This leads to more than
28 an order of magnitude enhancement of the radiation power efficiency in whisker-based, compared
29 to crystal-based devices. These results are in good agreement with presented experimental data.

30 **Keywords**

31 Terahertz sources; Josephson junctions; High-temperature superconductivity; Numerical mod-
32 elling;

33 **Introduction**

34 Low radiation power efficiency is a key problem of terahertz (THz) sources of electromagnetic
35 waves (EMW), colloquially known as “the THz gap” [1]. Tunable, monochromatic, continuous-
36 wave (CW), compact and power-efficient THz sources are required for a broad variety of applica-
37 tions [1]. However, their radiation power efficiency (RPE) is rapidly decreasing with decreasing
38 frequency. Despite a remarkable progress achieved by semiconducting quantum cascade lasers
39 (QCL’s) [2,3], their RPE drops well below a percent level at low THz frequencies [4-6]. Further-
40 more, operation of QCL is limited by thermal smearing of quantum levels, which becomes signif-
41 icant at frequencies $f \lesssim k_B T/h$, where k_B and h are Boltzmann and Planck constants and T is
42 the operation temperature. For room temperature, $T = 300$ K, this frequency is $f \approx 6.25$ THz.
43 QCL’s have to be cooled down in order to operate at significantly lower primary frequencies [4-6].
44 Although room temperature operation of QCL’s at low frequencies can be achieved via mixing and
45 down conversion of the higher primary frequency, this comes at the expense of a dramatic reduc-
46 tion of RPE [2,3,5,7,8].
47 Layered high-temperature superconductor $\text{Bi}_2\text{Sr}_2\text{CaCu}_2\text{O}_{8+\delta}$ (Bi-2212) may provide an alterna-
48 tive technology for creation of cryogenic THz sources [9-21]. Bi-2212 represents a natural stack of
49 atomic scale intrinsic Josephson junctions (IJJ’s) [22-25]. Josephson junctions have an inherently
50 tunable oscillation frequency, $f_J = (2e/h)V$, where e is electron charge and V is the bias voltage

51 per junction. The frequency is limited only by the superconducting energy gap, which can be in ex-
52 cess of 30 THz for Bi-2212 [26,27]. A broad range tunability of emission in the whole THz range
53 1 – 11 THz has been demonstrated from small Bi-2212 mesa structures [14].

54 Operation of Josephson emitters is limited by two primary obstacles: self-heating and impedance
55 matching. Josephson devices stop operating when their temperature exceeds the superconducting
56 critical temperature T_c . Self-heating in Bi-2212 mesa structures has been intensively studied [27-
57 36]. Although T_c of Bi-2212 may be quite high, up to ≈ 95 K [27], self-heating is substantial due
58 to a low heat conductance of superconductors. Self heating limits the maximum bias voltage that
59 can be reached without critical overheating of the mesa and, therefore, the maximum achievable
60 frequency and the emission power. Furthermore, as pointed out in Ref. [37], self-heating creates
61 a general limitation for the maximal achievable emission power for any cryogenic device (not only
62 superconducting). Taking into account the limited cooling power of compact cryo-refrigerators
63 (sub-Watt at low T), a device with RPE $\sim 1\%$ would not be able to emit significantly more than 1
64 mW. Therefore, larger emission power from cryogenic sources may only be achieved via enhance-
65 ment of RPE. The maximum achievable RPE is 50% in the case of perfect matching of the device
66 microwave impedance with that for open space [38]. However, the reported RPE of Bi-2212 THz
67 sources is much smaller [14] due to a significant impedance mismatch. Therefore, improvement
68 of THz sources requires proper design of cooling elements to handle self-heating, and impedance
69 matching microwave antennas, to improve RPE.

70 In this work we analyze design aspects of THz sources based on Bi-2212 mesa structures. Ther-
71 mal and radiative properties are studied for two types of devices containing either a conventional
72 large single crystal, or a whisker. We present numerical simulations for various geometrical con-
73 figurations and parameters and make a comparison with experimental data. It is demonstrated that
74 the structure and the geometry of both the superconductor and the electrodes are playing important
75 roles. Electrodes provide an effective heat sink channel and help in reduction of self-heating. They
76 also influence radiative properties. However, this influence is opposite for crystal-based (worsen)
77 and whisker-based (improve) devices. The superconductor geometry is also crucial. Devices based

78 on large crystals suffer from a large parasitic capacitance at the overlap between the crystal and
 79 the electrodes. It prevents good impedance matching and reduces RPE. The overlap is avoided in
 80 whisker-based devices. Moreover, the whisker itself, together with electrodes, forms a turnstile
 81 (crossed-dipole) antenna, facilitating good impedance matching. We show that this leads to more
 82 than an order of magnitude enhancement of RPE, compared to crystal-based devices. Those re-
 83 sults are in good agreement with experimental data, which demonstrate that THz emission from
 84 whisker-based device is much larger than from crystal-based devices with the same geometry.

85 Experimental results

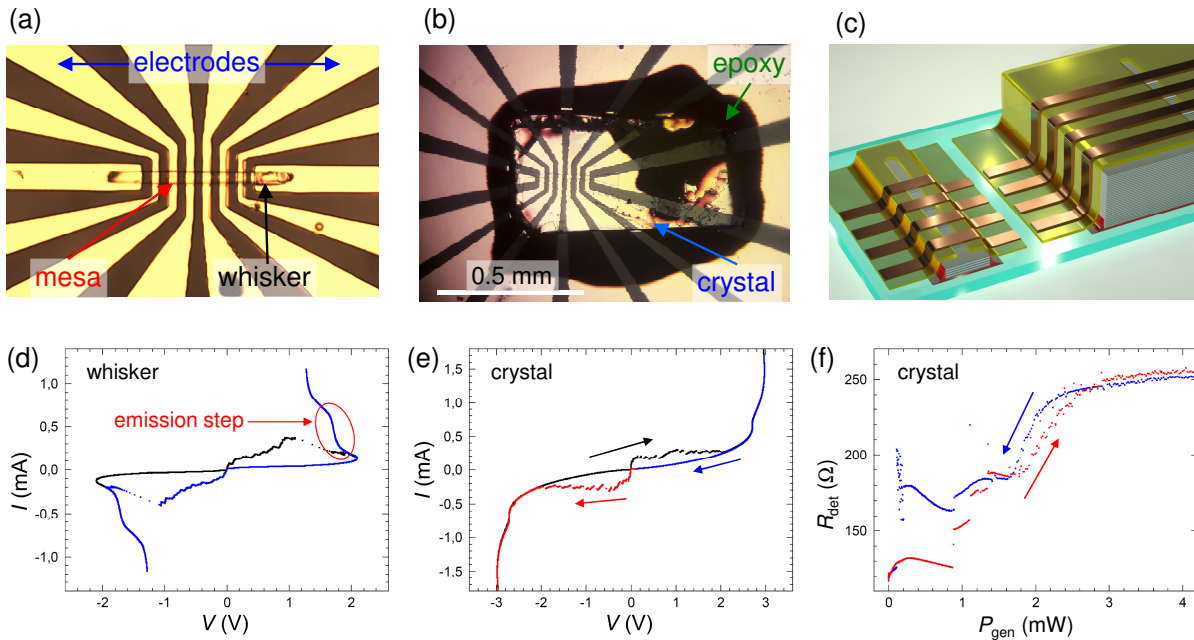


Figure 1: Optical images of (a) whisker and (b) crystal-based devices with similar electrode geometries. (c) A sketch of both devices. Panels (d) and (e) show Current-Voltage characteristics of mesa structures on (d) whisker and (e) crystal-based devices. (f) On-chip generation-detection experiment for the crystal-based device. Here an ac-resistance of the detector mesa is shown as a function of the total dc-dissipation power, $P_{gen} = IV$, of the generator mesa, corresponding to the I - V in (e). The monotonous increment of R_{det} at large P_{gen} corresponds to self-heating. The (small) non-monotonous detector response at $P_{gen} \lesssim 1.5$ mW is due to THz emission from the generator mesa.

86 Figures 1 (a) and (b) show optical images of two studied devices. They have a similar geometry
 87 and were fabricated using the same procedure. The main difference is that the device in (a) is made

88 using a whisker; and in (b) using a conventional large single crystal. Panel (c) shows sketches of
89 both devices. Bi-2212 whiskers have typical aspect ratios 100:10:1 in a , b , and c crystallographic
90 directions [39]. Our whiskers have typical dimensions of several hundreds of microns in a , 20 –
91 40 μm in b and just few μm in c -axis direction. In case (b) a big conventional single crystal is used
92 with sizes of almost a mm^2 in the $a - b$ plane and several hundreds of micrometers in the c -axis
93 direction.

94 The fabrication process starts by gluing a corresponding crystal on a $5 \times 5 \text{ mm}^2$ sapphire substrates
95 using an epoxy glue. The crystal is cleaved at ambient conditions. After that the sample is immedi-
96 ately put into a deposition chamber and a protective gold layer $\sim 60 - 80 \text{ nm}$ is deposited to avoid
97 surface passivation. Next, a line pattern in photoresist is made with the length 100 – 200 μm and
98 the width 5 – 15 μm on a flat portion of Bi-2212 surface, followed by Argon ion etching of unpro-
99 tected parts of Au and Bi-2212, deposition of insulating SiO_2 or CaF_2 layers and a lift-off of the
100 photoresist at the line. The depth of Bi-2212 etching at this stage ($d \sim 200 - 400 \text{ nm}$) defines the
101 height of mesas and the number of IJJ's in the device, $N = d/s$, where $s \simeq 1.5 \text{ nm}$ is the interlayer
102 spacing between double CuO layers in Bi-2212. After that top metallization Ti/Au layer with the
103 total thickness $\sim 200 \text{ nm}$ is deposited. Finally several electrodes, crossing the line in a perpendic-
104 ular direction, are made by photolithography and Ar-ion etching. Mesa structures are formed at the
105 overlap between the line and the electrodes, as indicated in Fig. 1 (a).

106 Figs. 1 (d) and (e) show current-voltage (I - V) characteristics of mesas at whisker and crystal-based
107 devices, respectively. The I - V 's are fairly similar. They contain multiple branches due to one-by-
108 one switching of IJJ's from the superconducting to the resistive state. The number of junctions is
109 ~ 200 for the whisker and ~ 300 for crystal mesas. Both the Bi-2212 crystal and the whisker have
110 similar suppressed $T_c \sim 65 - 70 \text{ K}$ and low critical current densities of IJJs in the mesas, $J_c \sim 100$
111 A/cm^2 . This indicates a strongly underdoped state of Bi-2212 [40].

112 Radiative properties of our whisker-based devices were analyzed in Ref. [37]. A significant EMW
113 emission at $f \simeq 4.2 \text{ THz}$ with a record-high RPE reaching 12% was reported. The emission occurs

114 at the step in the I - V , marked in Fig. 1 (d). To avoid repetitions we address the reader to Ref. [37]
 115 for details.

116 In Fig. 1 (f) we show results of in-situ THz generation- detection experiment on the crystal-based
 117 device from Fig. 1 (b). We follow the procedure developed in Ref. [14], where details of the tech-
 118 nique can be found. We use the mesa with the I - V shown in Fig. 1 (e) as a generator, and an-
 119 other mesa nearby as a switching current detector. The detector mesa is biased by a small ac-
 120 current and the generator by a dc-current in the same range as in Fig. 1 (e). Fig. 1 (f) shows the
 121 ac-resistance of the detector mesa, R_{det} , as a function of the dissipation power in the generator
 122 mesa, $P_{gen} = IV$. It is anticipated that self-heating is monotonous (approximately linear) with
 123 dissipation power, while the emission is nonmonotonous [14,37] because it occurs at certain bias
 124 voltages, corresponding to geometrical resonances in the mesa [14,23,25]. From Fig. 1 (f) it can
 125 be seen that there is a general trend for monotonous increment of R_{det} with increasing P_{gen} , which
 126 is the consequence of crystal heating. On top of it there is a small non-monotonous signal at 0.5
 127 mW $\lesssim P_{gen} \lesssim 1.5$ mW, which can be attributed to THz emission. This is qualitatively similar to
 128 results reported earlier for small mesas on crystal-based devices [14]. For whisker-based mesas the
 129 ratio of emission to self-heating responses is quantitatively different: The emission peak $R_{det}(P_{gen})$
 130 is much larger than the monotonous self-heating background (see Fig. 2 (a) in Ref. [37]). Since
 131 the dissipation power is similar for both devices (see Fig. 3 (f) in Ref. [37]), this indicates a much
 132 larger RPE in the whisker-based device.

133 Numerical results

134 To understand the reported difference between crystal and whisker-based devices and to suggest
 135 possible optimizations of THz sources, we performed numerical modelling using Comsol Multi-
 136 physics. Below we present simulations of thermal and radiative properties calculated using Heat
 137 Transfer and RF modules, respectively.

138 **Modelling of heat transfer**

139 Generally, analysis of self-heating in Bi-2212 mesas is a complex non-linear problem [27,29-31,33,
140 35]. Simulations presented below are made for the base temperature $T_0 = 10$ K and for sizes similar
141 to the actual devices, shown in Fig. 1: substrate size $5 \times 5 \times 0.3$ mm³, crystal size $1 \times 1 \times 0.3$ mm³,
142 whisker size $300 \times 30 \times 3$ μm³ and mesa size $30 \times 30 \times 0.3$ μm³. Epoxy layer beneath the Bi-2212
143 crystal is 1 μm thick. The monocrystalline sapphire substrate has a very good thermal conductivity,
144 κ , at low T . The substrate is well thermally anchored with the boundary condition at the bottom
145 surface $T = T_0$. Due to the good thermal conductivity, the temperature variation in the substrate
146 is negligible and we may neglect its $\kappa(T)$ dependence. Therefore, we use $\kappa = 3000$ W/K⁻¹m⁻¹
147 for the sapphire substrate at $T \sim 10$ K [41]. To the contrary, the epoxy used for gluing Bi-2212
148 crystals, has a poor heat conductance at low T . We do not consider its T -dependence because it
149 acts just as a heat blocking layer, which we assume to have $\kappa = 0.0025$ W/K⁻¹m⁻¹. On the other
150 hand, it is necessary to take into account actual $\kappa(T)$ dependencies for the other two materials, Bi-
151 2212 and polycrystalline gold electrodes. At low T both have linear $\kappa(T)$. For Bi-2212 we assume
152 $\kappa(T) = 0.1 T(\text{K})$ W/K⁻¹m⁻¹ [42] with an anisotropy $\kappa_{ab}/\kappa_c = 8$ [43]. For a polycrystalline gold
153 thin film we use $\kappa(T) = 3 T(\text{K})$ W/K⁻¹m⁻¹ [31]. The heat is introduced via a dissipation power of
154 1 mW with a constant density in the mesa volume.

155 Figure 2 represents heat-transfer simulations for a whisker without an electrode. Panels (a) and (b)
156 show sketches of the device and the x - z cross-section through the mesa (not in scale). Figs. (c-e)
157 show the temperature distribution for the case when the sample is placed in vacuum: (c) top view,
158 (b) x - z cross-section through the mesa (stretched by a factor 3 in the vertical direction), and (e) T -
159 distribution in the mesa (stretched by a factor 50 in the vertical direction). In this case the heat can
160 only sink into the substrate. As seen from Fig. 2(d), the epoxy layer between the substrate and the
161 whisker blocks heat flow into the substrate and causes a substantial heating of the whole whisker
162 with the maximum temperature in the center of the mesa reaching $T_{max} = 85.2$ K. Figs. 2(f-h) show
163 simulations for the same device in the exchange ⁴He gas. Clearly, it helps to cool down the device,
164 although self-heating still remains substantial, $T_{max} = 56.7$ K.

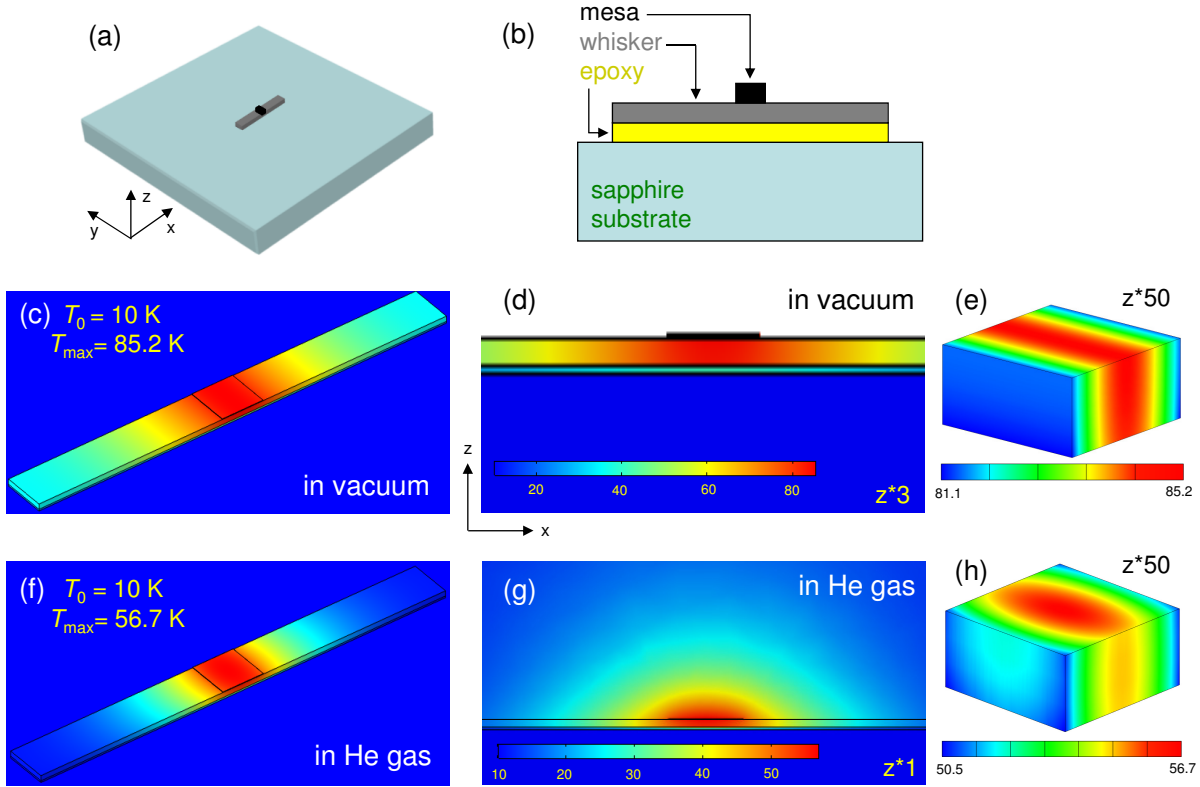


Figure 2: Heat transport in a whisker-based device without electrodes. (a) A sketch of the device and (b) a cross-section through the mesa (not in scale). (b-e) Calculated temperature distribution for the device in vacuum. (f-h) The same for the device in exchange He gas.

165 Figure 3 represents simulations for the whisker-based device with the top Au electrode. Outside the
 166 whisker the electrode is in a direct contact with the sapphire substrate (no epoxy). This creates a
 167 good thermal sink and, as a result, T_{max} falls to ~ 23 K. Addition of the exchange gas doesn't play a
 168 major role in this case because the main heat sink channel is provided by the electrode, acting as a
 169 heat spreading layer [28].

170 Figure 4 shows temperature distribution in a crystal-based device in vacuum (a) without electrodes
 171 and (b) with electrodes. The main difference is that unlike in the whisker-device, Fig. 2, there is no
 172 major temperature jump in the epoxy layer between the crystal and the substrate. This occurs be-
 173 cause the heat resistance of the epoxy layer is inversely proportional to the total in-plane x - y area.
 174 Due to a much larger crystal area this heat resistance is negligible, despite a poor heat conductivity
 175 of epoxy. Adding an electrode and He exchange gas further reduces self-heating, but their effect
 176 is not as profound as for the whisker-device, Fig. 3, due to the effective heat sink channel into the

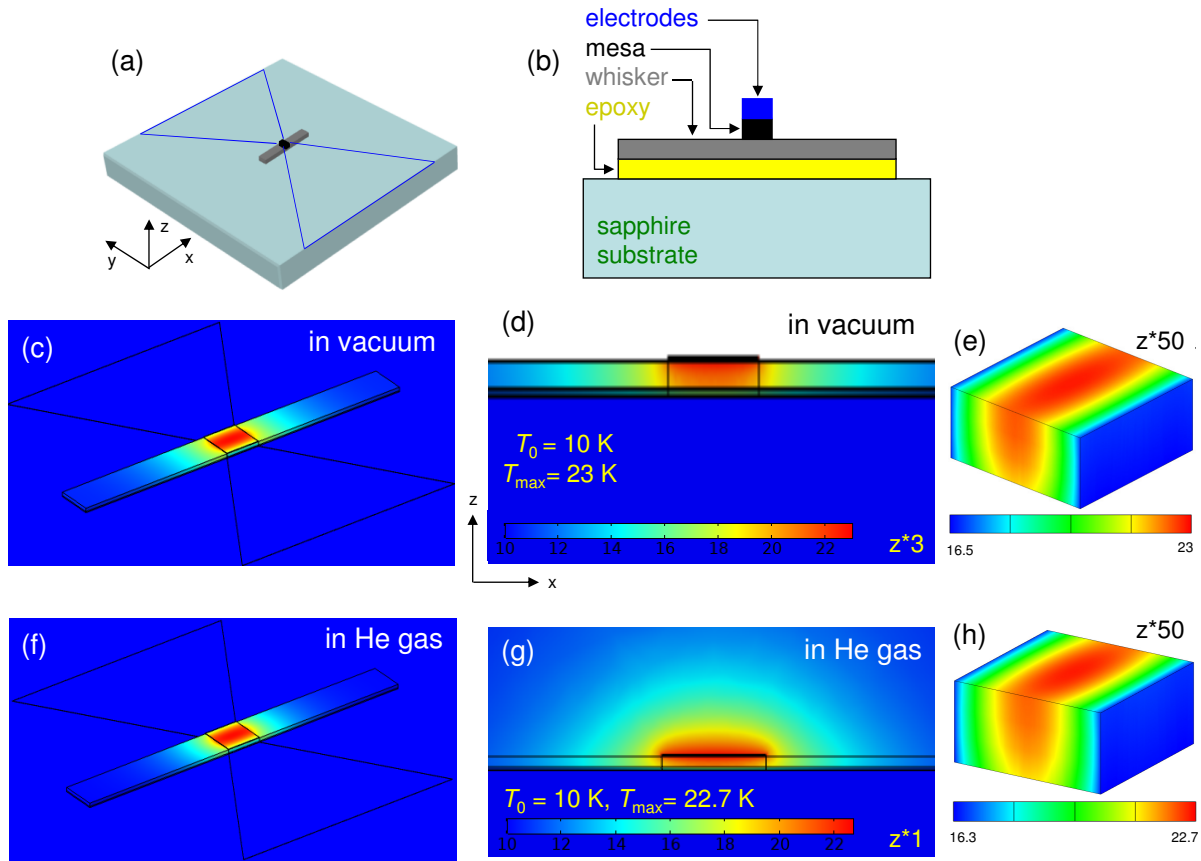


Figure 3: Heat transport in a whisker-based device with an electrode. (a) A sketch of the device and (b) a cross-section through the mesa (not in scale). (b-e) Calculated temperature distribution for the device in vacuum. (f-h) The same for the device in exchange He gas.

177 substrate. Of course, the effectiveness of this channel depends on the thickness of the epoxy layer.
 178 In simulations above we assumed a fixed thickness of $1 \mu\text{m}$ both for the whisker and the large crys-
 179 tal. However, in reality the thickness depends on the quantity of applied epoxy. Significantly larger
 180 quantities are required for gluing large crystals, which, due to capillary forces, results in a larger
 181 thickness of epoxy. Concurrently thinner than $1 \mu\text{m}$ epoxy layers can be achieved for gluing tiny
 182 whiskers. Therefore, the extent of self-heating in our simulations, Figs. 2, 3 and 4, is only indica-
 183 tive. For a real device it will depend on the actual geometry, sizes and thicknesses.

184 Modelling of radiative properties

185 For calculation of THz properties, a mesa (the source) is modelled as a lumped port with a fixed
 186 voltage amplitude. Unlike the heat transfer problem, this problem is linear so that the results di-

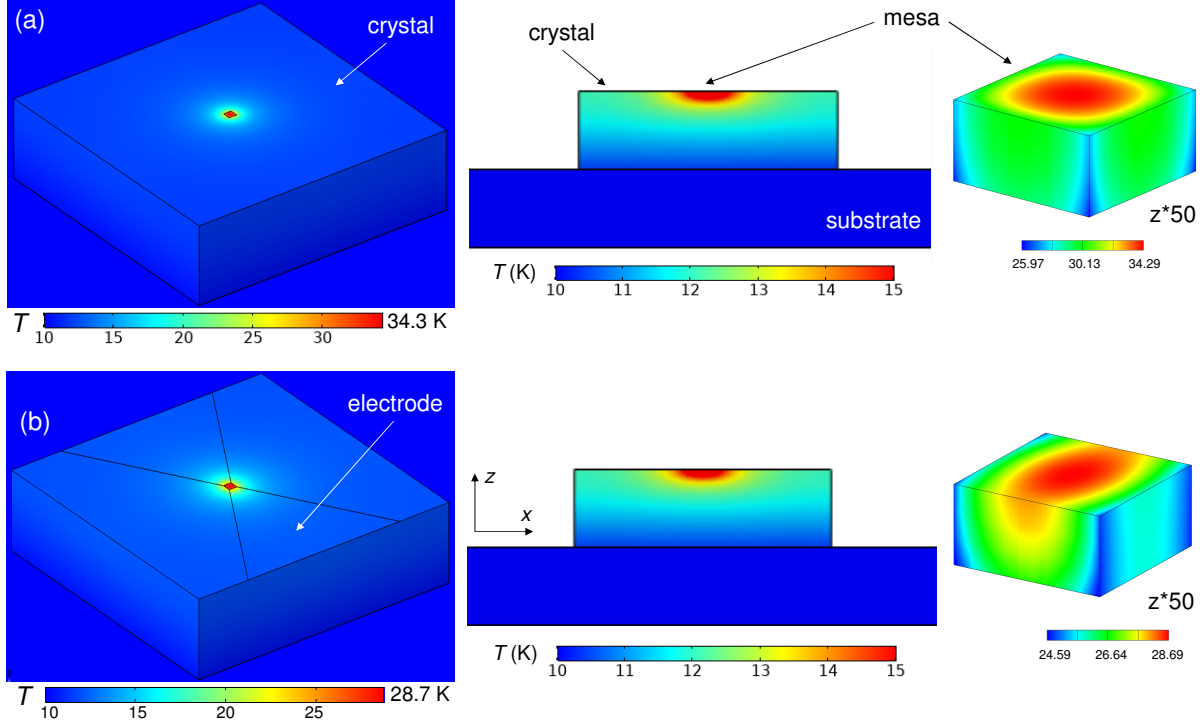


Figure 4: Heat transport in a crystal-based device in vacuum (a) without electrodes, (b) with electrodes. Left panel represent top views, middle panels - the x - z cross-section through the mesa, and right panels the mesa (expanded by factor 50 in z -direction).

187 rectly scale with the source amplitude. To simplify the perception, we use the amplitude of 1 Volt.
 188 Simulations are made in a sphere with the radius, R , which is chosen to be at least two times larger
 189 than the largest device size and the wavelength in vacuum. A perfectly matching layer with the
 190 thickness $0.1 R$ is added outside the sphere to avoid reflections. We checked that the presented re-
 191 sults do not depend on R and, therefore, properly describe far-field characteristics.
 192 Figure 5 represents radiative characteristics for three device geometries, sketched in the leftmost
 193 panels: (a) a mesa (red) on a large crystal (black) with an attached metallic electrode (yellow),
 194 mounted on a dielectric substrate; (b) a mesa on a large crystal with a capping metallic layer,
 195 without electrode; (c) a mesa on a thin whisker (black) with an attached electrode. Simulations
 196 are performed for $f = 1$ THz and the sizes are selected relative to the wavelength in vacuum,
 197 $\lambda_1 = 300 \mu\text{m}$: the substrate and the in-plane crystal size, whisker and electrode lengths are
 198 $\lambda_1/2 = 150 \mu\text{m}$; the substrate height is $\lambda_1/4 = 75 \mu\text{m}$; the in-plane mesa size, whisker and
 199 electrode widths are $\lambda_1/8 = 37.5 \mu\text{m}$; the crystal height is $\lambda_1/10 = 30 \mu\text{m}$; mesa and whisker

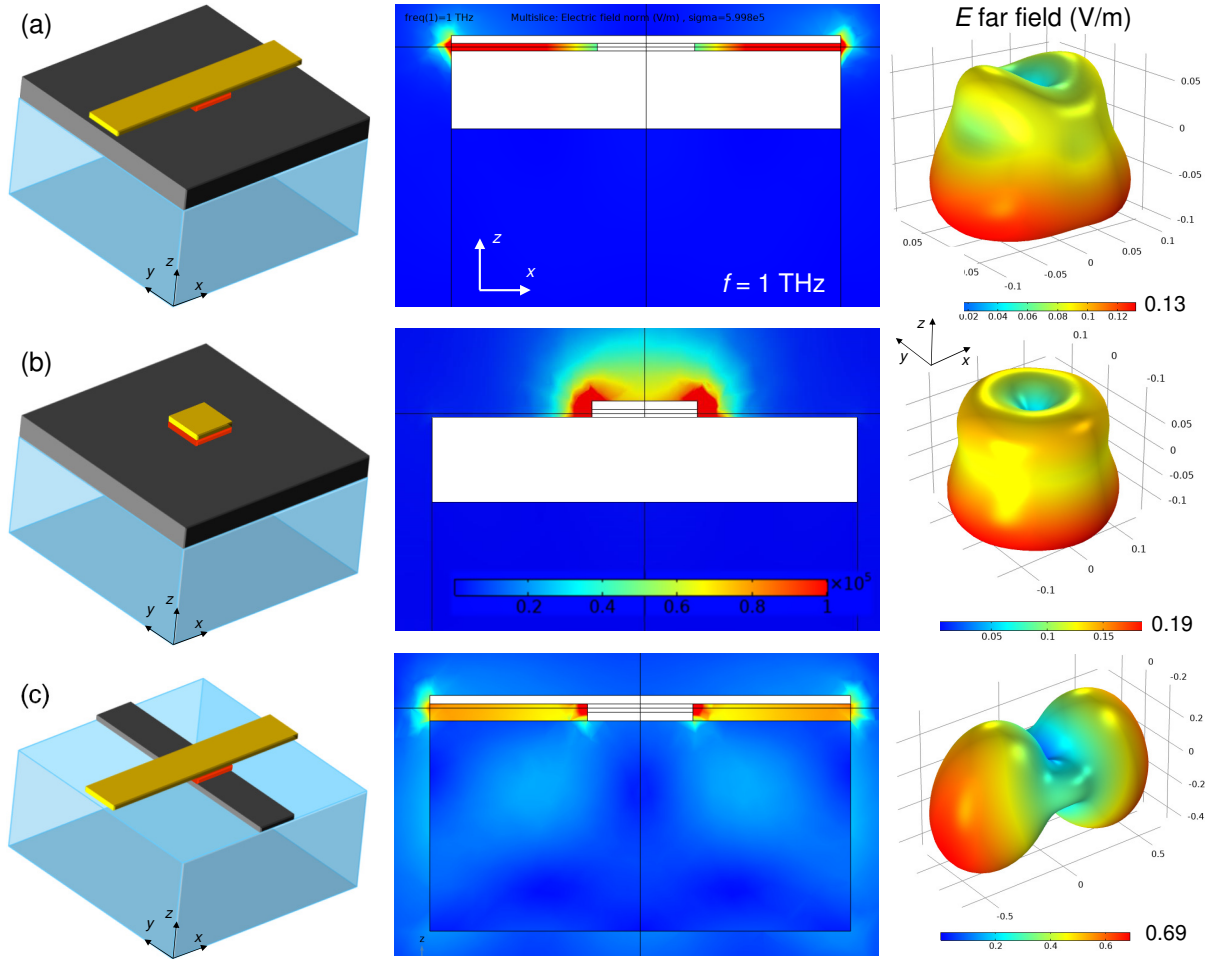


Figure 5: Simulated radiative properties at $f = 1$ THz for (a) crystal based device, (b) crystal-based device without electrodes, and (c) whisker-based device. Left panels show sketches of devices; middle panels - electric field amplitudes in the x - z cross-section through the mesa; right panels represent radiation patterns for the electric field amplitude in the far-field (outside the simulation sphere). Note a strong field concentration between the crystal and the electrode in (a).

200 heights, the electrode thickness is $\lambda_1/100 = 3 \mu\text{m}$; the simulation sphere radius $R = 2\lambda_1$ and
 201 the perfectly matching layer thickness $0.2 \lambda_1$. The sizes and parameters are chosen to be similar
 202 (but not identical) to studied samples in order to optimize the mesh size and the calculation time.
 203 Therefore, such simulations serve for a qualitative illustration of the difference between crystal and
 204 whisker-based devices and the role of the electrodes. Electrode and whisker conductivity is set to
 205 $\approx 6 \times 10^5 (\Omega\text{m})^{-1}$ and relative dielectric permittivity of the substrate $\epsilon_r = 10$. Dielectric losses are
 206 not considered, $\tan(\delta) = 0$. Middle panels in Fig. 5 show local distributions of electric field ampli-
 207 tudes in the $x - z$ cross-section, going through the mesa. The same color scale is used, indicated in

208 the middle panel of Fig. 5 (b). Rightmost panels represent far-field radiation patterns (directional-
209 ity diagrams) of the electric field amplitude outside the simulation sphere.

210 From comparison of middle panels in Figs. 5 (a) and (c) it can be seen that the electric field distri-
211 bution is significantly different. In the crystal-based device the field is locked between the electrode
212 and the crystal. This occurs because the electrode is laying on top of the crystal, forming together
213 a parallel plate capacitor. The field is trapped inside this capacitor and does not go neither in the
214 substrate, nor open space in the top hemisphere (with exception of small stray fields). If we take a
215 realistic specific capacitance $C_{\square} \sim 1 \text{ fF}/\mu\text{m}^2$ and electrode area $37.5 \times 150 \mu\text{m}^2$, we obtain for $f = 1$
216 THz that the capacitive impedance is very small $|Z_C| = 1/2\pi f C \simeq 0.03 \Omega$, much smaller than the
217 wave impedance of the free space, $Z_0 = \sqrt{\mu_0/\epsilon_0} \simeq 377 \Omega$. This leads to trapping of EMW in the
218 electrode/crystal capacitance, which shunts open space and prevents emission.

219 To the contrary, for the whisker-based device, Fig. 5 (c), the field goes out of the mesa as can be
220 seen from the brighter overall tone of the pattern in the middle panel. The EMW propagation is
221 particularly well seen in the bottom hemisphere due to formation of a standing wave pattern in
222 the substrate. It is induced by reflections at the substrate/vacuum interfaces caused by a signifi-
223 cant difference in refractive indices. Emission of EMW is associated with a cross-like structure of
224 the whisker device, as sketched in the leftmost panel of Fig. 5 (c). It obviates direct overlap of the
225 whisker and the electrode and prevents appearance of the large parasitic capacitance. This cross-
226 like structure resembles the turnstile (crossed-dipole) antenna geometry, which facilitates good
227 impedance matching with open space.

228 The difference between crystal and whisker-based devices is also reflected in the far-fields charac-
229 teristics, shown in the rightmost panels of (a) and (c). The maxim field amplitudes, E_{max} , marked
230 in bottom right corners, are significantly different: 0.13 V/m for crystal and 0.69 V/m for whisker-
231 based device. Since the emitted power is proportional to E_{max}^2 , the RPE of the whisker-based de-
232 vice is almost 30 times larger than for the crystal-based. This indicates a good impedance matching
233 of the whisker device and a poor matching for the crystal device. To further demonstrate the detri-
234 mental role of the parasitic electrode/crystal capacitor, in Fig. 5 (b) we considered the case with a

235 mesa on a crystal without electrode and only with the capping top layer on the mesa. Such configura-
 236 tion is relevant for large mesas, contacted by a bonding wire [9]. Remarkably, the far-field emis-
 237 sion is larger, $E_{max} = 0.19$ V/m, in the absence of the electrode. This clearly shows that the elec-
 238 trode on top of the crystal does not help in impedance matching. To the contrary, it makes things
 239 worse due to formation of the large parasitic capacitance, shunting the EMW.

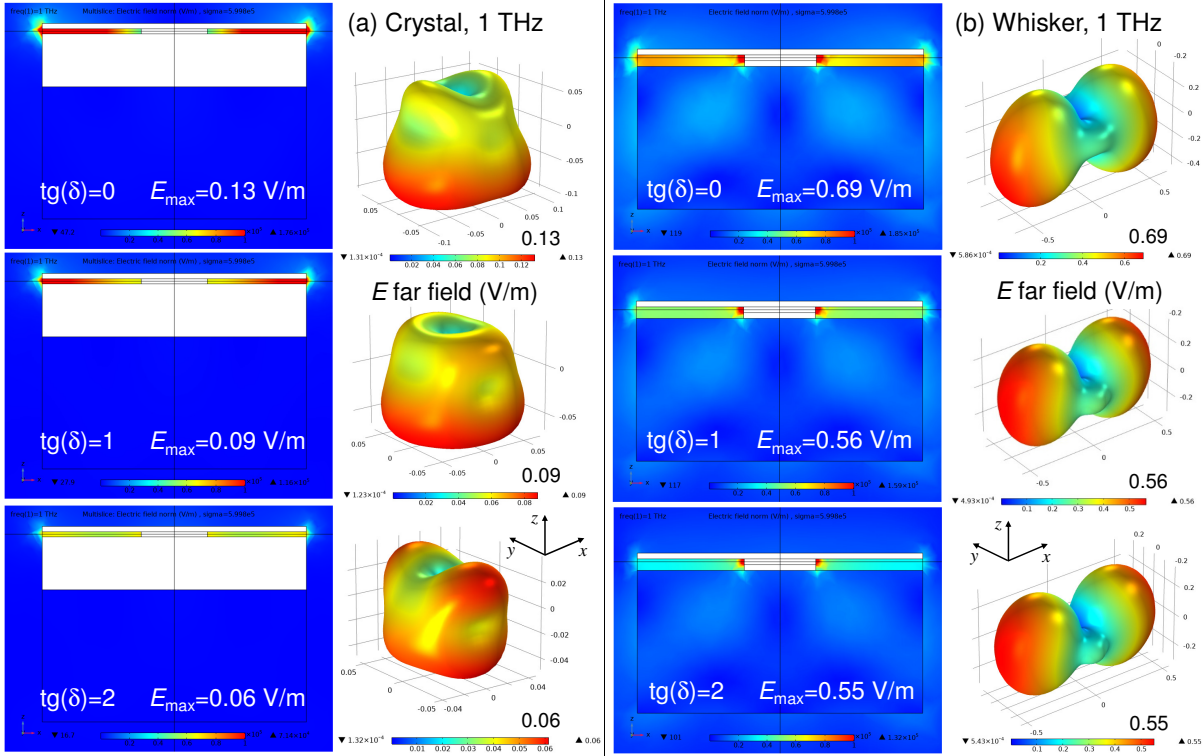


Figure 6: Variation of radiative properties with increasing dielectric losses $\tan(\delta) = 0$ (top row), 1 (middle row), and 2 (bottom row) for (a) crystal-based (two leftmost columns) and (b) whisker-based devices (two rightmost columns). Simulations are made at $f = 1$ THz. Note a rapid suppression of the far-field amplitudes in crystal-based devices.

240 Simulations presented in Fig. 5 are made for ideal dielectrics with zero dielectric losses, $\tan(\delta) =$
 241 0. The detrimental role of the parasitic crystal/electrode capacitance becomes much more pro-
 242 nounced if we take into account dielectric losses, which can be significant at THz frequencies. In
 243 Figure 6 we show variation of radiative properties of (a) crystal-based and (b) whisker based de-
 244 vices upon increasing dielectric losses in the insulating layer between the crystal and the electrode
 245 for crystal-based device and substrate and electrode for whisker-based device: $\tan(\delta) = 0$ (top),
 246 $\tan(\delta) = 1$ (middle), and $\tan(\delta) = 2$ (bottom row of panels). It is seen that for whisker-based

247 device dielectric losses only slightly reduce E_{max} from 0.69 V/m for $\tan(\delta) = 0$ to 0.55 V/m for
 248 $\tan(\delta) = 2$. For crystal-based device the relative reduction is significantly larger, from 0.13 V/m for
 249 $\tan(\delta) = 0$ to 0.06 V/m for $\tan(\delta) = 2$. As a result, the ratio of RPE for whisker and crystal devices
 250 increases from ~ 28 for $\tan(\delta) = 0$, to ~ 39 for $\tan(\delta) = 1$ and ~ 84 for $\tan(\delta) = 2$. This is a
 251 direct consequence of electric field concentration in the parasitic crystal/electrode capacitance of
 252 crystal-based devices.

253 Discussion

254 Josephson oscillators can provide unprecedented tunability in the whole THz range at a primary
 255 frequency [14]. However, being cryogenic devices, they are susceptible to self-heating, which lim-
 256 its both the achievable frequency range and the emission power. As pointed out in Ref. [37], the
 257 maximum emission power is limited by the cooling power of the device and the radiation power
 258 efficiency:

$$259 \quad P_{THz} < P_{cooling} \times RPE. \quad (1)$$

260 Enhancement of the effective cooling power requires implementation of special cooling elements at
 261 the device. Despite a significant progress in this direction [10,12,13,32,33,35,44], it is unlikely that
 262 a single emitter would be able to sustain the dissipation power above few tens of mW. The tolerable
 263 dissipation power can be significantly enhanced by spreading it between several smaller emitters
 264 [10,19] because smaller mesa structures are less prone to self-heating [14,27,28,30]. Such a strat-
 265 egy has been successfully proved for arrays of Josephson junctions [45-47], for which coherent
 266 emission from up to 9000 synchronized junctions was reported [46]. Yet, the ultimate dissipation
 267 power is limited by the cooling power of the cryostat itself. For compact cryorefrigerators it is in
 268 the range of 100 mW. As follows from Eq. (1), the source with RPE= 1% (which is good for THz
 269 sources) would not be able to emit more than $P_{THz} = 1$ mW. Therefore, further enhancement of
 270 the emission power requires enhancement of RPE. This in turn requires proper microwave design to

271 facilitate impedance matching with open space. The maximum RPE in case of perfect matching is
272 50% [38], implying that up to 50 mW emitted THz power could be achieved.

273 Above we considered design aspects of THz sources, which contribute to obviation of self-heating
274 and improvement of impedance matching. Several geometries of Bi-2212 devices were analyzed. It
275 is shown that geometries of both the Bi-2212 crystal and the electrodes are playing important roles.
276 Their effect, however, depends on the device type.

277 For crystal-based devices (using large crystals $\sim 1 \text{ mm}^2$ in the ab -plane, see Fig. 1 (b)) the size
278 of the crystal is playing opposite roles in device operation. On the one hand, a large ab -plane area
279 helps to spread heat into the substrate and reduces self-heating of the device, as seen from Fig. 4.
280 On the other hand, it leads to a large overlap area between the crystal and the top electrode. This
281 creates a large parasitic capacitance that shunts THz emission and suppresses RPE.

282 In whisker-based devices the situation is different. Here the electrode provides the main heat sink
283 channel, as shown in Fig. 3. The cross-like geometry prevents an overlap between the whisker and
284 the electrode, thus obviating the parasitic capacitance. Furthermore, the long whisker and the elec-
285 trode act as two arms of the crossed dipole (turnstile) antenna, facilitating good impedance match-
286 ing with open space.

287 The role of the substrate is also different. In crystal-based devices the large superconducting crys-
288 tal screens the EMW, so that there is practically no field in the substrate, see Figs. 5 (a) and (b). In
289 this case the substrate does not influence radiative properties. To the contrary, for whisker-based
290 device a significant fraction of EMW is going into the substrate due to its larger dielectric constan-
291 The difference of dielectric constants of the substrate and vacuum leads to internal reflections and
292 formation of standing waves in the substrate, see Fig. 5 (c). Therefore, the substrate acts as a di-
293 electric resonator and may strongly affect the radiation pattern of the device.

294 Presented numerical simulations provide a qualitative explanation of the reported difference in ra-
295 diative properties of whisker and crystal-based devices, shown in Figs. 1 (a) and (b). They explain
296 why RPE of whisker-based devices is much larger (by more than an order of magnitude, as follows

297 from Fig. 6). Those conclusions are in agreement with experimentally reported RPE, which is in
298 the range of $\lesssim 1\%$ for crystal-based [10,14] and up to 12% for whisker-based [37] devices.

299 **Conclusions**

300 To conclude, intrinsic Josephson junctions in layered high-temperature superconductor Bi-2212 can
301 provide an alternative technology for creation of tunable THz sources. In this work we analyzed
302 two main phenomena that limit performance of such devices: self-heating and low RPE caused
303 by impedance mismatching. We presented numerical simulations of thermal and radiative proper-
304 ties of Bi-2212 THz sources based on conventional large single crystals and needle-like whiskers.
305 Simulations are performed for various geometrical configurations and parameters. A comparison
306 with experimental data for crystal and whisker-based devices is made. It is demonstrated that the
307 structure and the geometry of both the superconductor and the electrodes are playing important
308 roles. Crystal-based devices suffer from a large parasitic capacitance due to an overlap between the
309 crystal and the electrodes. This prevents good impedance matching and reduces RPE. The over-
310 lap is avoided in whisker-based devices. Moreover, the whisker and the electrodes forms a turnstile
311 (crossed-dipole) antenna facilitating good impedance matching with open space. Our simulations
312 demonstrate that this may enhance the radiation power efficiency in whisker-based devices by more
313 than an order of magnitude compared to crystal-based devices, which is consistent with the experi-
314 mental data.

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